

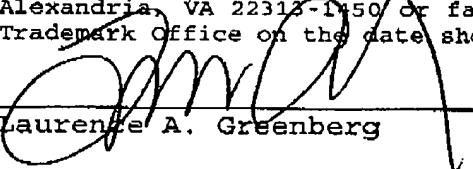
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Practitioner's Docket No.: MUH-12818

T-081 P01/14 U-014  
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Laurence A. Greenberg

September 2, 2005  
Date

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/675,049 Confirmation No.: 5871  
Applicant : Ioannis Dotsikas  
Filed : September 30, 2003  
Title : Method and Furnace for the Vapor Phase Deposition of Components onto Semiconductor Substrates with a Variable Main Flow Direction of the Process Gas  
Art Unit : 2818  
Examiner : Renee R. Berry  
Customer No. : 24131

A M E N D M E N T

Mail Stop Non Fee Amendment  
Hon. Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

S i r :

Responsive to the Office action dated June 20, 2005, kindly amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.